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APPLICATION N	0.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.	
10/620,002		07/14/2003	Dinesh Chopra	2269-4373.2US (00-0036.02	7481	
24247	7590	03/22/2005	EXAMINER		NER	
TRASK BRITT				UMEZ ERONIN	UMEZ ERONINI, LYNETTE T	
P.O. BOX	2550					
SALT LAKE CITY, UT		', UT 84110		ART UNIT	PAPER NUMBER	
				1765		
				DATE MAILED: 02/22/2005	•	

Please find below and/or attached an Office communication concerning this application or proceeding.

	Application No.	Applicant(s)					
Office Action Summans	10/620,002	CHOPRA ET AL.					
Office Action Summary	Examiner	Art Unit					
	Lynette T. Umez-Eronini	1765					
The MAILING DATE of this communication app Period for Reply	ears on the cover sheet with the c	orrespondence address					
A SHORTENED STATUTORY PERIOD FOR REPLY THE MAILING DATE OF THIS COMMUNICATION.  - Extensions of time may be available under the provisions of 37 CFR 1.13 after SIX (6) MONTHS from the mailing date of this communication.  - If the period for reply specified above is less than thirty (30) days, a reply  - If NO period for reply is specified above, the maximum statutory period w  - Failure to reply within the set or extended period for reply will, by statute, Any reply received by the Office later than three months after the mailing earned patent term adjustment. See 37 CFR 1.704(b).	36(a). In no event, however, may a reply be timed within the statutory minimum of thirty (30) days will apply and will expire SIX (6) MONTHS from a cause the application to become ABANDONE	nely filed s will be considered timely. the mailing date of this communication. D (35 U.S.C. § 133).					
Status							
1) Responsive to communication(s) filed on 07 No	ovember 2003.						
2a)☐ This action is FINAL. 2b)☒ This	action is non-final.						
3) Since this application is in condition for allowance except for formal matters, prosecution as to the merits is							
closed in accordance with the practice under E							
Disposition of Claims							
4)⊠ Claim(s) <u>1-25</u> is/are pending in the application.	4) Claim(s) 1-25 is/are pending in the application						
4a) Of the above claim(s) is/are withdrawn from consideration.							
5) Claim(s) is/are allowed.							
6) Claim(s) is/are rejected.							
7)⊠ Claim(s) <u>1-25</u> is/are objected to.							
8) Claim(s) are subject to restriction and/or	r election requirement.						
Application Papers	•						
9)☐ The specification is objected to by the Examine	r						
10)⊠ The drawing(s) filed on 14 July 2003 is/are: a)		y the Examiner					
Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).							
Replacement drawing sheet(s) including the correcti		• •					
11) The oath or declaration is objected to by the Examiner. Note the attached Office Action or form PTO-152.							
Priority under 35 U.S.C. § 119							
		(1)					
12) Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f). a) All b) Some * c) None of:							
The second of the phone of the							
<ul> <li>2. Certified copies of the priority documents have been received in Application No.</li> <li>3. Copies of the certified copies of the priority documents have been received in this National Stage</li> </ul>							
application from the International Bureau (PCT Rule 17.2(a)).							
* See the attached detailed Office action for a list of the certified copies not received.							
	The common copies that toosite	<b>.</b>					
Attachment(s)							
1) Notice of References Cited (PTO-892) 2) Notice of Draftsperson's Patent Drawing Review (PTO-948)	4) 🔲 Interview Summary ( Paper No(s)/Mail Da						
3) Information Disclosure Statement(s) (PTO-1449 or PTO/SB/08)		atent Application (PTO-152)					
Paper No(s)/Mail Date <u>7/14/03 &amp; 1/12/04</u> .	6)  Other:	11					
J.S. Patent and Trademark Office PTOL-326 (Rev. 1-04) Office Act	ion Summary Par	t of Paper No./Mail Date 20050228					



#### **DETAILED ACTION**

#### **Priority**

1. It is suggested that the current status of the present applications be updated.

### Claim Rejections - 35 USC § 102

2. The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless -

- (b) the invention was patented or described in a printed publication in this or a foreign country or in public use or on sale in this country, more than one year prior to the date of application for patent in the United States.
- 3. Claims 1-11, and 15-19 are rejected under 35 U.S.C. 102(b) as being anticipated by Hudson (US 5,972,792).

Hudson teaches a method of chemical-mechanical planarization of a substrate on a fixed abrasive polishing pad in which a planarizing solution is dispensed onto the pad (Abstract). The planarizing solution may be used to planarized titanium and aluminum on a tungsten plug, a titanium nitride barrier layer (column 4, lines 1-25) and copper (column 4, lines 50-52); has a pH of between 3.0 and 10.0 (column 4, lines 53-54); includes an oxidant such as ferric nitrate, hydrogen peroxide, potassium iodate, and bromine (column 4, lines 35-37 and 53-56); and has a mixture of 0.1%-1.0% benzotriazole, 0.1%-5.0% nitric acid, and deionized water (column 4, lines 56-65). The above read on,

A slurry for use in polishing a copper structure of a semiconductor device, the slurry being substantially free of abrasives.

Since Hudson uses a composition that is substantially free of abrasives as claimed by applicants, then using Hudson's slurry in the same manner as claimed in the present invention would inherently result in the slurry being formulated to substantially concurrently polish copper and a barrier material with the barrier material being removed at substantially the same rate as or at a slower rate than copper is removed, as **in claim 1**:

being formulated to oxidize copper at substantially the same rate as or at a faster rate than the barrier material is oxidized, **in claim 3**;

wherein, in the slurry, the barrier material and copper have substantially the same oxidation energies, in claim 4:

wherein, in the slurry, the barrier material has an oxidation energy of about 0.25 V more to about 0.20 V less than an oxidation energy of copper in said slurry **in claim** 5;

wherein, in the slurry, a rate of removal of the barrier material is up to about ten times slower than a rate of removal of copper, in claim 6;

wherein, in the slurry, a rate of removal of the barrier material is about two to about four times slower than a rate of removal of copper, in claim 7;

wherein the slurry is formulated to remove copper and the barrier material without substantially dissolving the barrier material that underlies remaining portions of copper, in claim 8;

wherein the slurry comprises at least one oxidizer, at least one pH control agent, and at least one inhibitor, in claim 9:

wherein the at least one oxidizer comprises at least one of an ammonium compound, a nitrate compound, and an amine compound, in claim 10; and

wherein the at least one oxidizer comprises at least one of hydrogen peroxide, potassium iodate, potassium permanganate, ammonium persulfate, ammonium molybdate, ferric nitrate, nitric acid, potassium nitrate, and ammonia, in claim 11.

Hudson also teaches planarizing with a silica-ceria fixed abrasive polishing pad (column 4, lines 38-39), which reads on the slurry being formulated for use with a fixed-abrasive polishing pad comprising at least one of aluminum dioxide, titanium dioxide, silicon dioxide, and cerium dioxide, in claim 2;

The said above also encompasses,

wherein the slurry has a pH of about 2 to about 6, in claim 15;

wherein the at least one inhibitor comprises about 0.05% to about 2% of the weight of said slurry, in claim 18; and

wherein the at least one inhibitor comprises about 0.05 to about 0.2% of the weight of said slurry, in claim 19.

The said above also reads on,

wherein the at least one inhibitor comprises at least one of an azole, an amine, and a ring compound, in claim 16; and

wherein the at least one inhibitor comprises at least one of benzenetriazole (BTA), mercaptobenzothiazole, tolytriazole, methylamine, diethylamine, pyridine,

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quinoline, dicyclohexamine nitrate, potassium silicate, ammonium borate, ammonium phosphate, and potassium dichromate, in claim 17.

## Claim Rejections - 35 USC § 103

- 4. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:
  - (a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.
- 5. This application currently names joint inventors. In considering patentability of the claims under 35 U.S.C. 103(a), the examiner presumes that the subject matter of the various claims was commonly owned at the time any inventions covered therein were made absent any evidence to the contrary. Applicant is advised of the obligation under 37 CFR 1.56 to point out the inventor and invention dates of each claim that was not commonly owned at the time a later invention was made in order for the examiner to consider the applicability of 35 U.S.C. 103(c) and potential 35 U.S.C. 102(e), (f) or (g) prior art under 35 U.S.C. 103(a).
- 6. Claims 12-14 and 21-25 are rejected under 35 U.S.C. 103(a) as being unpatentable over Hudson (US '792) as applied to claim 1 above, and further in view of Chopra (US 6,419,554 B2).

Chopra differs in failing to teach at least one pH control agent as recited in claim 14; and to specify the percent by weight of the oxidizer as recited in claims 12-13 and 23-24 and the complexing agent as recited in claims 21-22.

Chopra teaches a planarizing solution comprising buffering agents such as ammonium oxalate and ammonium phosphate (same as applicants' pH control agent and complexing agent) and which range from 0% to 10 % by weight (column 6, lines 6-9 and 16-17) and oxidizers, which range from 1% to 10 % by weight (column 6, line 54-58 and 65 – column 7, line 1).

Since the Chopra reference teaches an abrasive free solution comprising the specific concentration of oxidizer and complexing agent are known, then it would have been obvious to one having ordinary skill in the art at the time of the claimed invention to modify Hudson by using Chopra's concentration of oxidizer and complexing agent that would effectively accomplish the applicants' disclosed slurry because it has been held that there is no invention where the difference in proportions is not critical and was ascertained by routine experimentation because the determination of workable ranges is not considered inventive. See In re Swain and Adams, 70 USPQ 412 (CPA 1946).

Hudson in view of Chopra differs in failing to teach wherein the slurry removes copper at a temperature of about 27°C or cooler.

Unless the operational conditions of a process is specified, it would have been obvious to one having ordinary skill in the art at the time of the claimed invention to assume applicants' slurry was used at standard pressure (1 atm) and temperature of 25°C, which lies within a temperature range of about 27 °C or cooler that would effectively accomplish the applicants' disclosed slurry because it has been held that there is no invention where the difference in proportions is not critical and was

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ascertained by routine experimentation because the determination of workable ranges

is not considered inventive. See In re Swain and Adams, 70 USPQ 412 (CPA 1946).

Any inquiry concerning this communication or earlier communications from the

examiner should be directed to Lynette T. Umez-Eronini whose telephone number is

571-272-1470. The examiner is normally unavailable on the First Friday.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's

supervisor, Nadine Norton can be reached on 571-272-1465. The fax phone number

for the organization where this application or proceeding is assigned is 703-872-9306.

Information regarding the status of an application may be obtained from the

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NADINE G. NORTON SUPERVISORY PATENT EXAMINER

March 17, 2005

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